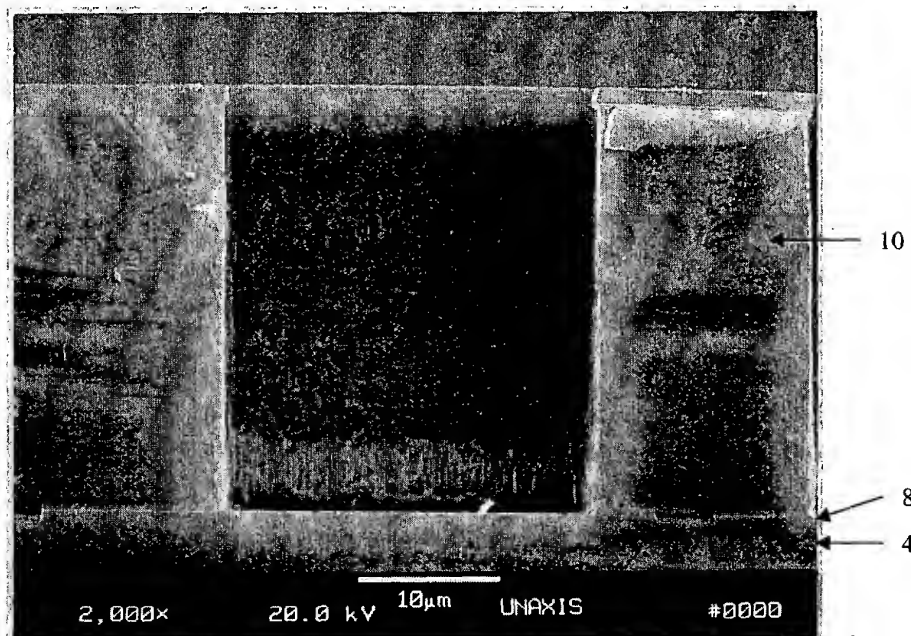
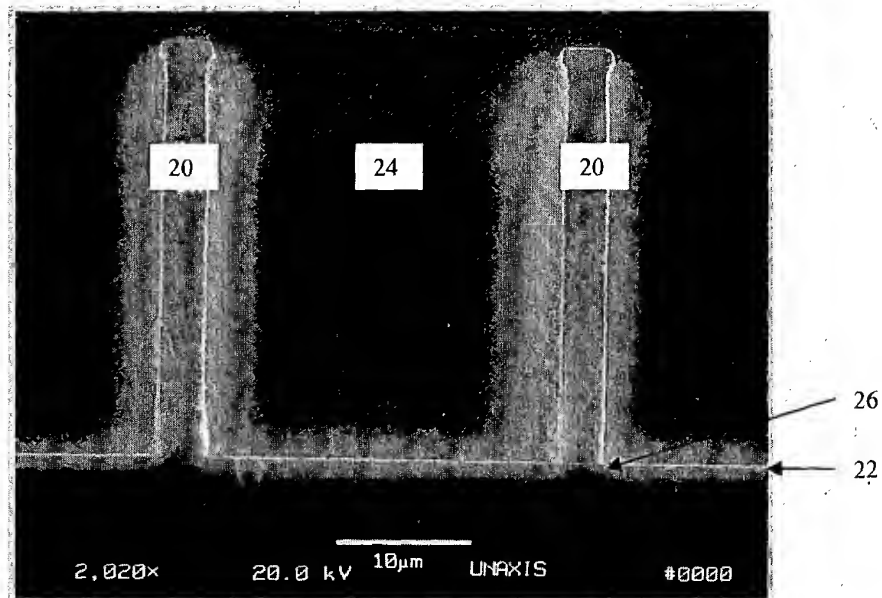


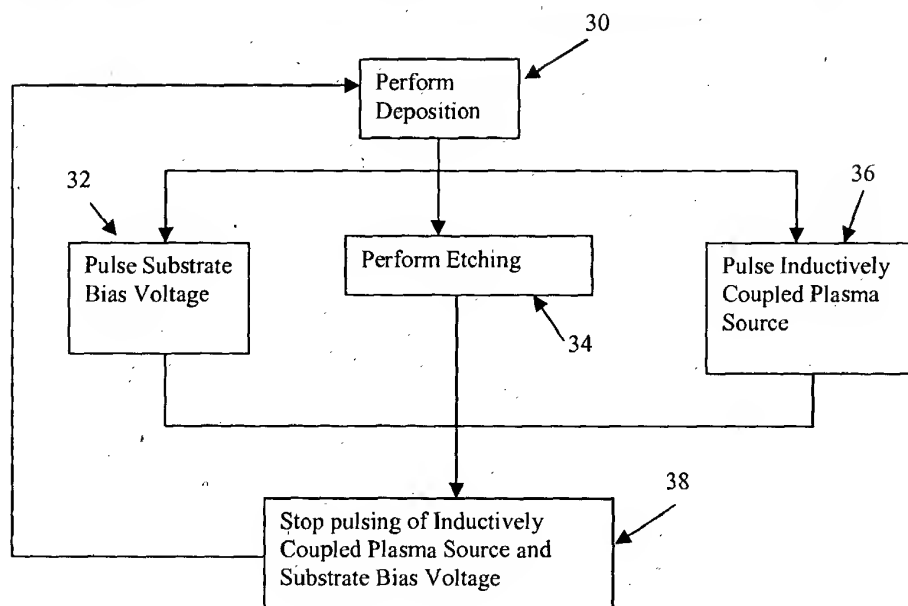
**Figure 1 SOI feature etched using no pulsing (prior art)**



**Figure 2 Same feature as Fig 1, using ICP pulsing**



**Figure 3** Narrow features etched in an SOI structure using ICP pulsing



**Fig. 4**